

SWS-500

“WET” TYPE POU ABATEMENT



www.gst-international.com
sales@gst-international.com
+1.408.685.2199

Exhaust solution for high-volume semiconductor manufacturing



Applications

- > Semiconductor processes

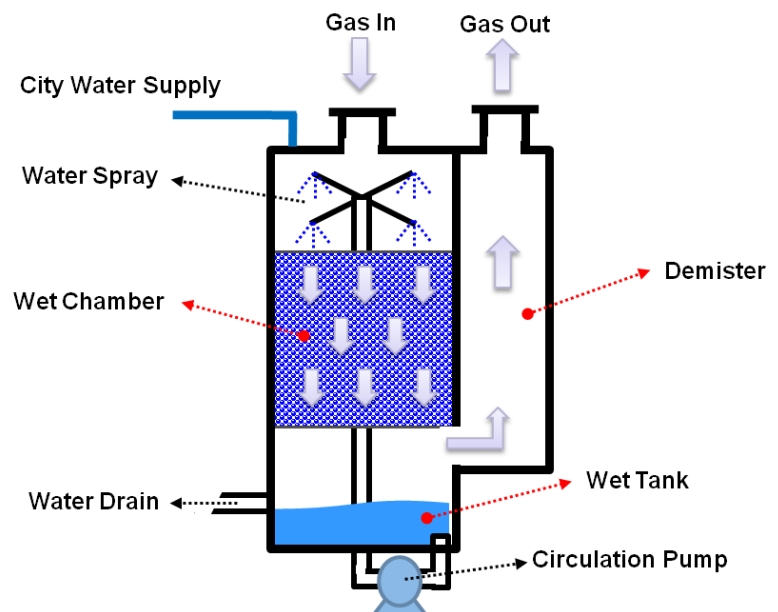
Features

- > Inlet N2 Purge
- > Low pressure drop design
- > Transparent PVC wet chamber
- > Large volume demister chamber for gravitational settling
- > Natural (gravity) drain standard / pump drain option
- > pH adjust option: NaOH injection
- > Inlet manifold option

Benefits

- > Low operating costs
- > Simple and easy maintenance
- > Corrosion resistant wet chamber construction
- > Minimal water mist carry over to exhaust header
- > HVM (high volume manufacturing) proven

System Specifications



- Total System Capacity: **500 slm**
- Per Inlet Capacity: **100 slm**
- Process Inlets: **VP125 PVC flange single entry**
(inlet manifold options available - KF40/50 up to 8 inlets)
- MTBF: **> 8,000 hours**
- MTRR: **< 2 hour**
- MTTP: **< 1.5 hour**

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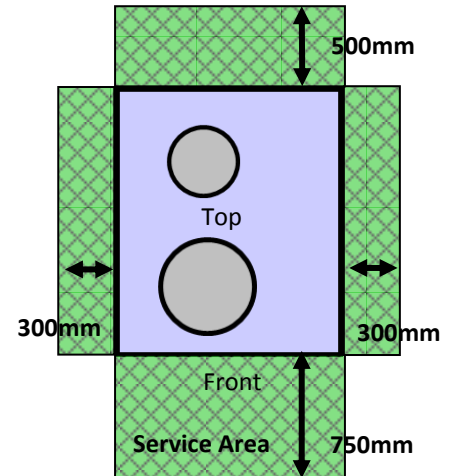
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Dimensions and Weight

SWS-500

Dimension 750 x 850 x 1800(2100)
(W x D x H in mm)

Weight 180
(kg)



Utilities

Item	Type	Typical Usage	Typical Usage
Electricity	208VAC 1 Phase	0.8 KW	10A service
CDA	5 ~ 6.5 kg/cm ²	3 LPM	¼" SS compression
GN2	3 ~ 6 kg/cm ²	20 SLM	¼" SS compression
City Water	3 ~ 6 kg/cm ²	6 L/min	½" SS compression
Drain Water (gravity)	Acid Drain	6 L/min	32A PVC union
Drain Water (pump)	Acid Drain	6 L/min	15A PVC union
Gas Exhaust	-50 ~ -80 mmH2O	1 m ³ /min	VP125 Flange
Cabinet Exhaust	-30 ~ -60 mmH2O	1 m ³ /min	MF100 Flange

Environment

- Clean and dry environment
- Temperature: 5 ~ 27 °C
- Relative Humidity: < 55%

Abatement Noise Level

- Normal operation at ≤80 dB(A)